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## APPLICANTS

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## \*\* CONTINUING DATA \*\*\*\*\*

This application is a DIV of 09/390,142 09/03/1999 PAT 6,368,189  
 which is a CON of 09/294,547 04/19/1999 PAT 6,309,290  
 which is a CIP of 09/261,112 03/03/1999 PAT 6,231,428

OK TE

## \*\* FOREIGN APPLICATIONS \*\*\*\*\*

None TE

## IF REQUIRED, FOREIGN FILING LICENSE GRANTED

\*\* 01/31/2002

Foreign Priority claimed <input type="checkbox"/> yes <input checked="" type="checkbox"/> no	STATE OR COUNTRY CA	SHEETS DRAWING 24	TOTAL CLAIMS 18	INDEPENDENT CLAIMS 6
35 USC 119 (a-d) conditions met <input type="checkbox"/> yes <input checked="" type="checkbox"/> no <input type="checkbox"/> Met after Allowance				
Verified and Acknowledged Examiner's Signature <i>[Signature]</i> Initials <i>TE</i>				

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## TITLE

Apparatus and method for chemical-mechanical polishing (CMP) head having direct pneumatic wafer polishing pressure

☐ All Fees